

Claudia Hamann

List of Publications by Year in descending order

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Version: 2024-02-01

31
papers

395
citations

759055

12
h-index

794469

19
g-index

31
all docs

31
docs citations

31
times ranked

390
citing authors

#	ARTICLE	IF	CITATIONS
1	Review Article: Active scanning probes: A versatile toolkit for fast imaging and emerging nanofabrication. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2017, 35, .	0.6	44
2	Formation of Polymer and Nanoparticle Doped Polymer Minirods by Use of the Microsegmented Flow Principle. <i>Chemical Engineering and Technology</i> , 2007, 30, 341-346.	0.9	38
3	Pattern-generation and pattern-transfer for single-digit nano devices. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2016, 34, .	0.6	34
4	Large area fast-AFM scanning with active "Quattro" cantilever arrays. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2016, 34, .	0.6	27
5	Room-temperature single dopant atom quantum dot transistors in silicon, formed by field-emission scanning probe lithography. <i>Journal of Applied Physics</i> , 2018, 124, .	1.1	27
6	Field emission from diamond nanotips for scanning probe lithography. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2018, 36, .	0.6	26
7	Automated synchrogram analysis applied to heartbeat and reconstructed respiration. <i>Chaos</i> , 2009, 19, 015106.	1.0	23
8	Atomic force microscope integrated with a scanning electron microscope for correlative nanofabrication and microscopy. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2018, 36, .	0.6	22
9	Six-axis AFM in SEM with self-sensing and self-transduced cantilever for high speed analysis and nanolithography. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2016, 34, .	0.6	17
10	Experimental study of field emission from ultrasharp silicon, diamond, GaN, and tungsten tips in close proximity to the counter electrode. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2018, 36, .	0.6	13
11	Low-energy electron exposure of ultrathin polymer films with scanning probe lithography. <i>Microelectronic Engineering</i> , 2017, 177, 78-86.	1.1	12
12	Nanofabrication by field-emission scanning probe lithography and cryogenic plasma etching. <i>Microelectronic Engineering</i> , 2018, 192, 77-82.	1.1	12
13	Simulation of field emission from volcano-gated tips for scanning probe lithography. <i>Microelectronic Engineering</i> , 2017, 177, 19-24.	1.1	11
14	2D Simulation of Fowler-Nordheim Electron Emission in Scanning Probe Lithography. <i>Journal of Nanomaterials & Molecular Nanotechnology</i> , 2016, 06, .	0.1	11
15	Identification of response classes from heavy metal-tolerant soil microbial communities by highly resolved concentration-dependent screenings in a microfluidic system. <i>Methods in Ecology and Evolution</i> , 2015, 6, 600-609.	2.2	10
16	Scanning probe-based high-accuracy overlay alignment concept for lithography applications. <i>Applied Physics A: Materials Science and Processing</i> , 2017, 123, 1.	1.1	10
17	Field-emission scanning probe lithography tool for 150%mm wafer. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2018, 36, .	0.6	10
18	Charged particle single nanometre manufacturing. <i>Beilstein Journal of Nanotechnology</i> , 2018, 9, 2855-2882.	1.5	7

#	ARTICLE	IF	CITATIONS
19	Initiation of atrial fibrillation by interaction of pacemakers with geometrical constraints. Journal of Theoretical Biology, 2015, 366, 13-23.	0.8	6
20	Sharp GaN nanowires used as field emitter on active cantilevers for scanning probe lithography. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	5
21	Theoretical investigation of the enhancement factor for a single field emitter in close proximity to the counter electrode. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, 06JL01.	0.6	5
22	Enabling Adaptive and Enhanced Acoustic Sensing using Nonlinear Dynamics. , 2020, , .		5
23	Field-emission scanning probe lithography with self-actuating and self-sensing cantilevers for devices with single digit nanometer dimensions. , 2018, , .		5
24	Complex oscillation modes in the Belousov-Zhabotinsky reaction by weak diffusive coupling. Physical Review E, 2019, 99, 022202.	0.8	4
25	High-throughput process chain for single electron transistor devices based on field-emission scanning probe lithography and Smart Nanoimprint lithography technology. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, 021603.	0.6	4
26	Single nano-digit and closed-loop scanning probe lithography for manufacturing of electronic and optical nanodevices. , 2018, , .		3
27	Irregular excitation patterns in reaction-diffusion systems due to perturbation by secondary pacemakers. Physical Review E, 2013, 87, 042904.	0.8	2
28	Optimising sodium silica gel for Ferrioin immobilization. Journal of Porous Materials, 2017, 24, 923-932.	1.3	1
29	Simulation of Fowler-Nordheim emission for scanning probe lithography. , 2017, , .		1
30	Optimized Adjustment of Single Action-potentials to Case-specific Atrial Physiology: Towards Clinical Implementation. , 0, , .		0
31	Fabrication of optical nanodevices through field-emission scanning probe lithography and cryogenic etching. , 2018, , .		0